**NanoGetters®**

**The Challenge**

When using some of the traditional non-evaporative getter technologies for the production of MEMS devices, there may be a problem regarding the generation of particles in the package. These particles are undesirable and could shift in the package over time. This could potentially cause major issues including electrical shorts and changes in resonant frequency.

**The Solution**

Materion’s NanoGetters® technology offers a superior alternative for vacuum packaging reliability. It uses proprietary materials and processes to eliminate the problem of stray gases trapped within device packaging. Since it is thin film-based, it is also particle-free. Some of the benefits include:

- Exhibits superior cleanliness
- Wafer-level, high vacuum (<1mTorr) encapsulation
- Longer-term vacuum stability
- High yield
- Can be deposited on variety of substrates
- Resists oxidation at room temperature

### Turnkey Solution for WLP Lid Wafers

**BENEFITS**

- Consistency in processes and product quality
- Compatibility with all MEMS technologies: polysilicon surface, bulk, silicon-on glass & LIGA micromachining
- Established technology leader for innovative thin film solutions
- ISO 9001:2008, ITAR compliant, AS9102 qualified

**APPLICATIONS**

- Optical devices
- IR sensors
- RF-MEMS
- Chemical sensors
- Microfluidic devices
- Accelerometers, gyroscopes
- Pressure & flow sensors
- Density meters
- Resonators
- Vacuum displays